# A Comparison of Si CMOS, SiGe BiCMOS, and InP HBT Technologies for High-Speed and Millimeter-Wave ICs

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*Abstract* — This paper presents an overview of Si MOSFET, SiGe HBT, and InP HBT device and circuit performance for broadband and tuned millimeter-wave applications. Implementations of CMOS-only, SiGe-HBT-only, SiGe BiCMOS, and InP-HBT 30-80 Gb/s high-speed circuit in production 130-nm SiGe BiCMOS and InP HBT technologies are compared.

*Index Terms* — Heterojunction bipolar transistor, silicongermanium, indium-phosphide, CMOS, BiCMOS, CM, lownoise amplifiers.

#### I. INTRODUCTION

As illustrated in Fig.1, production 90-nm CMOS, 130nm SiGe BiCMOS, and 1-µm InP HBT technologies from multiple foundries have demonstrated simultaneous  $f_T$  and  $f_{MAX}$  values exceeding 150 GHz. At the same time, advanced SiGe and InP HBTs with cutoff frequencies of 350 GHz and 450 GHz, respectively, are being developed by several groups. Not surprisingly, the last year has brought about a significant increase in the number of publications addressing millimeter-wave (mm-wave) and high-speed digital ICs with data rates exceeding 40 Gb/s [1]-[6]. Interest in mm-wave circuits has been kindled by the potentially large automotive radar market (60 million cars were produced world-wide in 2002) and by the newly licensed 70-GHz band for wireless gigabit Ethernet. In each case, volumes are predicted to reach \$1.5B in 5 years [7]. This paper presents an overview of Si MOSFET, SiGe HBT, and InP HBT devices. Their performance in broadband and tuned mm-wave circuits implemented in production 130-nm SiGe BICMOS [8] and InP HBT [9] technologies is compared.

### II. TRANSISTOR PERFORMANCE COMPARISON

## A. $f_T$ , $f_{MAX}$

The  $I_{DS}$ - $V_{GS}$  characteristics of very deep submicron MOSFETs biased in saturation exhibit two distinct regions. At low effective gate voltages ( $V_{eff} = V_{GS} - V_T$ ) the well-known, long-channel square law applies. At larger gate voltage, the characteristics become linear. The

boundary between the two regions corresponds roughly to the  $V_{eff}$  at which  $f_T$  and  $f_{MAX}$  reach their peak values. For example, in 130-nm n-MOSFETs [10], for  $V_{eff}$  lower than 0.2 V, the experimental behaviour is accurately captured by simple expressions that describe the linear increase in  $g_m$ ,  $f_T$ , and  $f_{MAX}$  with  $V_{GS}$ , as well as their dependence on device geometry ( $N_{f_0}$   $W_f$ ) and on the series resistances  $R_s$ ,  $R_g$ ,  $R_d$  and the channel resistance  $R_i$ . Beyond  $V_{eff} = 0.4$  V,  $g_m$ ,  $f_T$  and  $f_{MAX}$  become almost independent of gate voltage, underscoring the linearity of MOSFETs when biased at or beyond peak  $f_T$ .

$$2\pi f_{\rm T} \approx \frac{N_{\rm f} C_{\rm OX} \mu_{\rm n} \frac{W_{\rm f}}{l_{\rm G}} (V_{\rm GS} - V_{\rm T})}{\frac{2}{3} C_{\rm ox} N_{\rm f} W_{\rm f} l_{\rm G} + (C_{\rm GDO} + C_{\rm GSO}) N_{\rm f} W_{\rm f} + C_{\rm GBO} N_{\rm f} l_{\rm G}}$$
(1)

$$f_{MAX} \approx \frac{J_T}{2\sqrt{\frac{R_{gsq}W_f^2}{I2(3)l_g}(g_{ds}^{'}+2\pi f_T C_{gd}^{'})+g_{ds}^{'}(R_i^{'}+R_s^{'})}}$$
(2)



Fig.1 Measured  $f_T$  and  $f_{MAX}$  as a function of drain/collector current for a) 180-nm, 130-nm, and 90-nm n-MOSFETs, and b) for SiGe and InP HBTs [12].

 $C'_{gd}$ ,  $g'_{ds}$ ,  $R'_{i}$ ,  $R'_{s}$  indicate unit gate width parameters. As the minimum feature size of MOSFETs reaches 100 nm, the gate-source and gate-drain overlap and fringing capacitances ( $C_{GSO}$ ,  $C_{GDO}$ ,  $C_{GBO}$ ) become comparable to the internal gate capacitance and contribute significantly to performance degradation in digital and RF circuits. Shrinking the unit gate finger width  $W_f$  below 1 µm and/or contacting the gate on both sides does little to improve  $f_{MAX}$  and noise figure while severely reducing  $f_T$  [10].

As a result of the constant-field scaling rules being applied to every new CMOS generation since the 0.5-µm technology node,  $V_{eff}$  at peak  $f_T$  scales with the technology node and is therefore more difficult to predict and use in analytical circuit design. However, the drain current per total device width at which the peak  $f_T$  and  $f_{MAX}$  of Si n-MOSFETs occurs is 0.25 to 0.3 mA/µm, independent of technology node, as shown in Fig.1a. In p-MOSFETs, the corresponding value is 0.125 to 0.15 mA/µm. This fundamental property of MOSFETs can be applied to simplify CMOS CML-logic and mm-wave circuit design using current-centric rather than  $V_{eff}$  bias techniques. This approach is similar to the one used in bipolar circuits which rely on peak  $f_T$  bias. For comparison, in SiGe and InP HBTs the peak  $f_T/f_{MAX}$  current density per emitter length is 1.2 mA/µm and 2mA/µm, respectively, Fig. 1b. Given the comparable  $f_T$  and  $f_{MAX}$  of production CMOS, SiGe BiCMOS, and 1-µm InP HBT technologies, the differences in their circuit behaviour can be explained by transconductance, gate/base resistance, and slew rate.

## B. Noise and narrow-band noise matching sensitivity

As in the case of  $f_{MAX}$ , due to the increase of the gate resistance with  $W_f$ , the MOSFET minimum noise factor  $F_{MIN}$  is a strong function of gate geometry. Layout, therefore, becomes an important differentiator between the performance of LNAs implemented in the same CMOS technology node by different designers, even when similar circuit topologies are employed.

$$F_{\rm MIN(MOS)} \approx 1 + 2k_1 \frac{f}{f_{\rm T}} \sqrt{g_{\rm m}^{'} R_{\rm s}^{'} + \frac{g_{\rm m}^{'} R_{\rm gsq} W_{\rm f}^{2}}{12(3) l_{\rm G}} + k_2 (1 + \omega^2 R_{\rm i}^2 C_{\rm gs}^2)}$$
(3)

In contrast, the  $F_{MIN}$  of HBTs is only weakly dependent on emitter length, making LNA design far more predictable across foundries and designers. In both SiGe and InP HBTs, the optimal  $F_{MIN}$  bias current is frequencydependent and considerably lower than the maximumgain bias, leading to a trade-off between noise and gain, Fig. 2.

$$F_{\rm MIN(HBT)} \approx 1 + \frac{1}{\beta} + \frac{f}{f_{\rm T}} \sqrt{\frac{I_{\rm C}}{2 \, V_{\rm T}}} (R_{\rm E} + R_{\rm b}) \left( 1 + \frac{f_{\rm T}^2}{\beta \, f^2} \right) + \frac{f_{\rm T}^2}{4 \, \beta \, f^2} \qquad (4)$$

At low current densities the bias dependence of  $F_{MIN(HBT)}$  is determined by the base resistance variation with bias current. In this respect, InP and SiGe HBTs exhibit quite

different behaviour. InP HBTs, with very high doping levels in the base, exceeding 10<sup>20</sup> cm<sup>-3</sup>, have practically constant base resistance which leads to a continuous decrease in  $F_{MIN}$  as the bias current is reduced. In SiGe HBTs, due to the lower base doping, the internal base resistance decreases with increasing bias current, leading to  $F_{MIN}(I_C)$  characteristics that exhibit a minimum when the base resistance thermal noise equals the collector shot noise. In contrast, in n-MOSFETs, the optimum  $F_{MIN}$  bias, approximately 0.13 mA/µm, is close to the maximum gain bias and occurs at the same current density, irrespective of frequency and of the technology node. This is a consequence of the fact that, when MOSFETs are biased in the saturation region,  $f_T$ ,  $f_{MAX}$ , and  $F_{MIN}$  are strongly dependent on the  $g_m(V_{GS})$  and  $g_m(V_{DS})$  characteristics.  $F_{MIN}$ reaches a minimum when  $g_m(V_{GS})$  peaks.





Fig. 2 *F<sub>MIN</sub>* and associated gain as a function of bias current at 36 GHz for 130-nm n-MOSFETs, SiGe and InP HBTs.

Si MOSFETs benefit from the lower transconductance and capacitance per unit gate width and from the layout dependence of gate resitance to achieve lower noise figures than those of SiGe and InP HBTs of comparable or higher  $f_T$  and  $f_{MAX}$ . However, these benefits are seldom achieved in practical implementations of tuned circuits at microwave and mm-wave frequencies. The very high noise resistance  $R_n$ , low optimum noise admittance  $Y_{sopt}$ , and high quality factor of the MOSFET input and noise impedances, in concert with the strong layout dependence, make CMOS circuits considerably more sensitive than HBT ones to process variations, impedance mismatch, and model inaccuracy.

$$\mathbf{R}_{\mathrm{n(MOS)}} \approx \frac{\mathbf{P}}{\mathbf{g}_{\mathrm{m}}} + (\mathbf{R}_{\mathrm{s}} + \mathbf{R}_{\mathrm{g}}); \quad \mathbf{R}_{\mathrm{n(HBT)}} \approx \frac{1}{2 \, \mathbf{g}_{\mathrm{m}}} + (\mathbf{R}_{\mathrm{E}} + \mathbf{R}_{\mathrm{b}})$$
(6)

$$Y_{sopt(MOS)} \approx \frac{f}{f_T R_n} \left[ \sqrt{P g_m (R_s + R_g)} - j P \right] \text{ where } P > \frac{2}{3}$$
(7)

$$Y_{sopt(HBT)} \approx \frac{f}{f_T R_n} \left[ \sqrt{\frac{g_m}{2} (R_E + R_b)} - j \frac{1}{2} \right]$$
(8)

## C. High-speed digital performance metrics

The open-circuit time constant (OCTC) of a chain of differential MOS-CML inverters and of a HBT-CML inverter chain with a stage-to-stage loading factor of k can provide a useful metric of the ultimate digital speed of these technologies.

$$\tau_{MOS} \approx \Delta V \frac{C_{gd} + C_{db}}{I_T} + \left(k + \frac{R_g}{R_L}\right) \Delta V \frac{C_{gs} + (1 - A_V)C_{gd}}{I_T}$$
(9)

$$\tau_{HBT} \approx \Delta V \frac{C_{\mu} + C_{cs}}{I_T} + \left(k + \frac{R_b}{R_L}\right) \Delta V \frac{C_{\pi} + (1 - A_V)C_{\mu}}{I_T}$$
(10)

 $A_V$  is the small signal voltage gain of the input transistor, typically -2 for MOS, and -1 for cascode HBT inverters, respectively, I<sub>T</sub> is the tail current,  $R_L$  is the load resistance, and  $\Delta V$  is the logic swing. The first term in the OCTC equations represents the voltage swing divided by the intrinsic slew rate of the device. The latter is larger in HBTs than in MOSFETs. For highest digital speed, the tail current of the MOS-CML inverter corresponds to the peak f<sub>T</sub> bias (i.e. each transistor in the differential pair is biased at 0.15 mA/µm). This allows full switching with a voltage swing of 450 mVp-p and 300 mVp-p in 130-nm and 90-nm CMOS, respectively. The HBT CML inverters have 250 mVp-p swing and are biased at a tail current 1.5 times the peak f<sub>T</sub> current density.

It has been recognized recently that the base resistance term is the major roadblock limiting the switching speed of SiGe HBT logic in the 120-GHz and 200-GHz SiGe HBT generations [13]. In MOS-CML, the gate resistance term can be rendered negligible through layout techniques by reducing the unit finger width. Based on the previous analysis, a novel BiCMOS-CML logic family has recently been proposed that employs a cascode stage consisting of a MOSFET common-source device followed by a common-base HBT [11]. Such a structure takes advantage of the large intrinsic slew rate of the HBT and of the small gate resistance of the MOSFET, resulting in faster switching speed than either MOS or HBT CML families. At the same time, as a result of the low MOSFET threshold voltage and superior  $f_T$  at low  $V_{DS}$  (Fig. 3) it operates with lower (less than 2.5 V) supply voltages than SiGe HBT ECL and CML logic.

$$\tau_{BiCMOS} \approx \Delta V \frac{C_{\mu} + C_{cs}}{I_T} + \left(k + \frac{R_g}{R_L}\right) \Delta V \frac{C_{gs} + C_{gd}}{I_T}$$
(11)

## III. CIRCUIT PERFORMANCE COMPARISON

By taking advantage of the fine-line, multi-level copper back-end of Si CMOS and SiGe BiCMOS technologies [8,12], designers can compensate for the higher silicon substrate loss to achieve similar transmission line [12] and inductor performance to that obtained on InP semiinsulating substrates [14]. Fig.4 compares measured data for 150-pH inductors fabricated on Si and InP substrates. *Q* factors reaching 15 at 50 GHz, and self-resonantfrequencies beyond 100 GHz are predicted in both cases. The stripe width is 2  $\mu$ m and 5  $\mu$ m, for the Si and InP inductors respectively, resulting in a 75% smaller footprint for the silicon implementation.



Fig. 3 Drain/collector voltage dependence of  $f_T$  in 130-nm n-MOSFETs and SiGe HBTs.



Fig. 4 Measured L and Q of Si and InP inductors.

InP HBT [9] and SiGe HBT broadband transimpedance amplifiers were designed using an algorithmic methodology to ensure that the minimum noise figure is achieved over the 3dB-bandwidth of the amplifier. Their  $50-\Omega$  noise figures, shown in Fig.5a, were measured onwafer up to 20 GHz and compared to that of a broadband CMOS amplifier [15] fabricated in the same 130-nm SiGe BiCMOS technology [8]. The noise of the InP and SiGe amplifiers is comparable in the 15-GHz to 20-GHz range. Below 15 GHz, the SiGe HBT amplifier has a singleended noise figure of 9.5 dB, 1.5 dB lower than that of the InP amplifier, and 7 dB better than that of the CMOS amplifier with resistively-matched inverter input stage. Large signal eye diagrams for all three circuits are shown in Figs. 5b, 5c, and 5d. The 130-nm CMOS amplifier operates from a 1.5-V supply with 300-mVp-p output swing per side. Its sensitivity is 10 mVp-p per side at 20 Gb/s and 100 mVp-p per side at 30 Gb/s. The InP amplifier operates from a 3.3-V supply and has a sensitivity of 8 mVp-p at 43 Gb/s [9] while the SiGe amplifier demonstrated an eye Q of 7 with a 2<sup>31</sup>-1 PRBS at 43 Gb/s for a single-ended 20 mVp-p input. The SiGe HBT circuit was operational with a supply voltage down to 1.9 V. The eye diagrams of an 80-Gb/s 2:1 MUX, implemented in a 150-GHz SiGe BiCMOS process [8] using the proposed BiCMOS logic, are shown in Fig. 6.



Fig. 5: a) (top left) Noise figure and eye diagrams of b)(top right) SiGe HBT comparator at 40Gb/s, c) InP comparator at 40 Gb/s (bottom left), and d) CMOS at 30 Gb/s (bottom right).



Fig.6: 80-Gb/s output eye of SiGe BiCMOS 2:1 MUX.

#### VI. CONCLUSION

Experimental device and circuit data, and simple analytical expressions of the main high-frequency FOMs of SiGe and InP HBTs have proved that, at comparable  $f_T$  and  $f_{MAX}$ , there is very little difference in their

performance in narrow-band mm-wave and in broadband and high-speed digital circuits. For the first time, starting with the 130-nm SiGe BiCMOS technology node, designers can take advantage of the comparable n-MOSFET and SiGe HBT speed to combine the two devices on the high-frequency signal path in truly BiCMOS topologies and thus realize low-voltage and lowpower mm-wave ICs in the 30-GHz to 80-GHz range.

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